



Docket No. 740819-418

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:

Kazuichiro ITONAGA et al.

Serial No. 09/662,004

Filed: September 14, 2000

For: METHOD OF FORMING INSULATING)
FILM AND METHOD OF)
FABRICATING SEMICONDUCTOR)
DEVICE) Date: October 9, 2003

)

) Group Art Unit: 2823

) Examiner: William M. Brewster

) Confirmation No. 9057

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CERTIFICATE OF MAILING OR TRANSMISSION
[37 CFR 1.8(a)]

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Signature: Deborah Movahhedi

Name: Deborah Movahhedi

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AMENDMENT AFTER FINAL

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Alexandria, VA 22313-1450

Sir:

In response to the Office Action mailed July 30, 2003, please consider the remarks and amendments in connection with the above-identified application.

Amendments to the Claims begin on page 2 of this paper.

Remarks begin on page 10 of this paper.

Replacement Drawings are appended to this paper.